

SHJ太陽電池における水素起因界面欠陥の発生機構

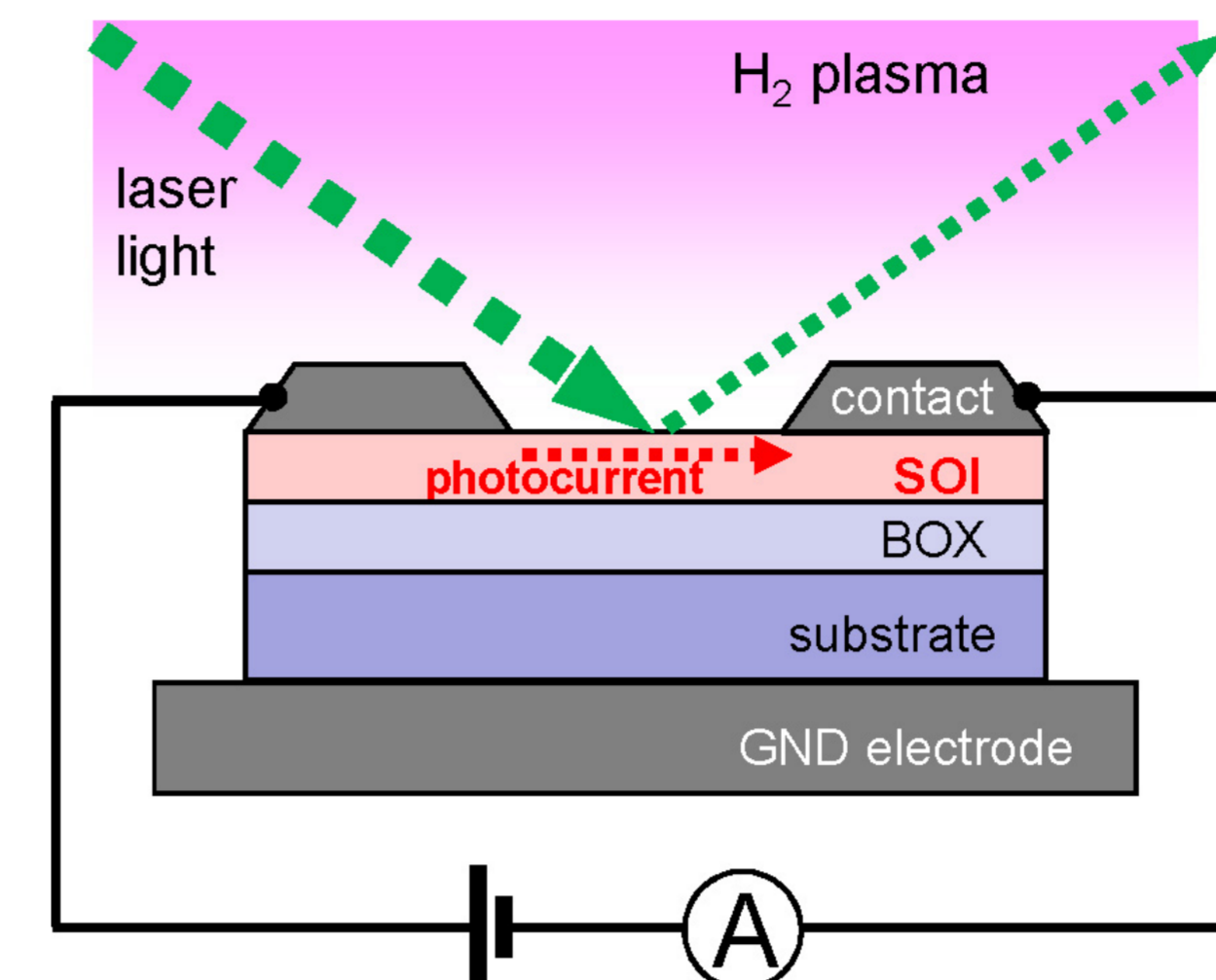
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Abstract

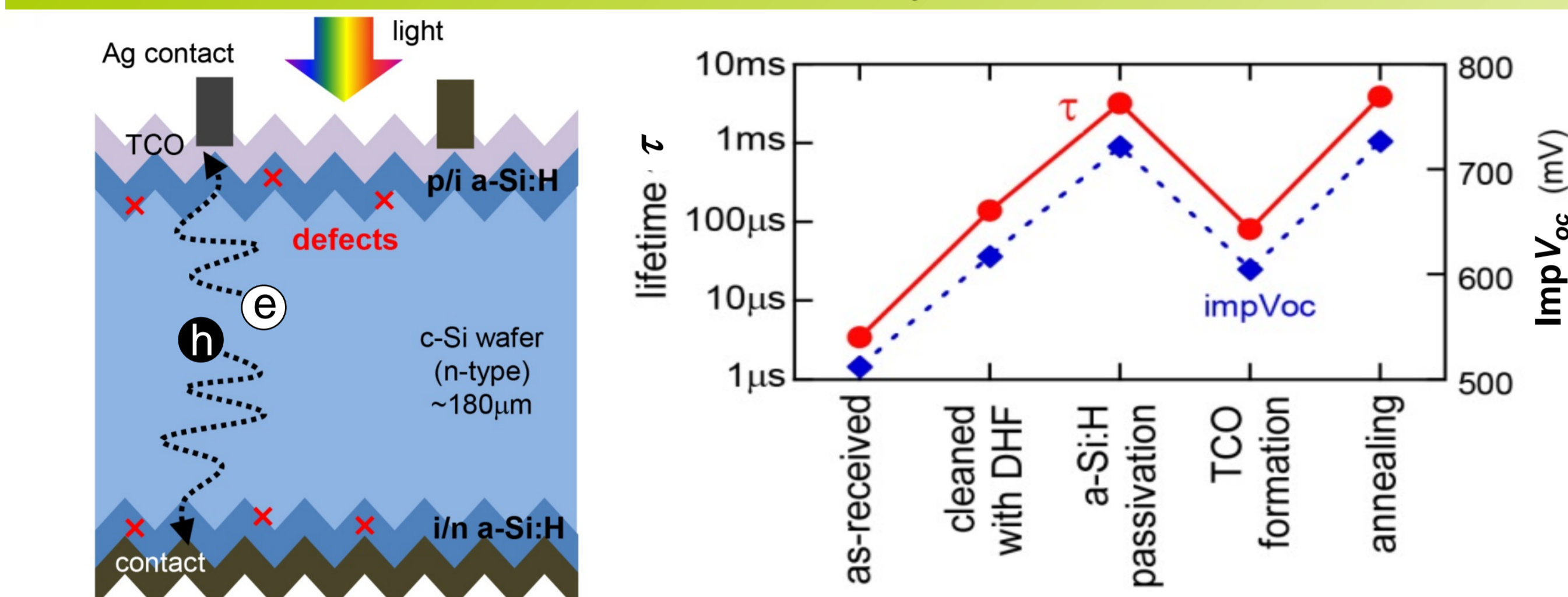
- **Hydrogen plasma-induced defects** in crystalline silicon have been studied, by using in-situ photocurrent measurement and spectroscopic ellipsometry.
- A hydrogen (H_2) plasma treatment causes **surface defects**, **bulk defects** and **surface disordered layer (DSL)**, depending on the treatment time.
- The defect formation strongly depends on the treatment time & treatment temperature.

Exp. Setup: In-situ real-time photocurrent measurement



- **Silicon on insulator (SOI)** is used as a sample for the photocurrent measurement.
- SOI is illuminated with a **semiconductor laser** (520nm, 1mW).
- The **photocurrent** is measured during H_2 plasma treatment and subsequent postannealing.
- In experiments, the **treatment time (Δt)** and **temperature (T)** are varied.

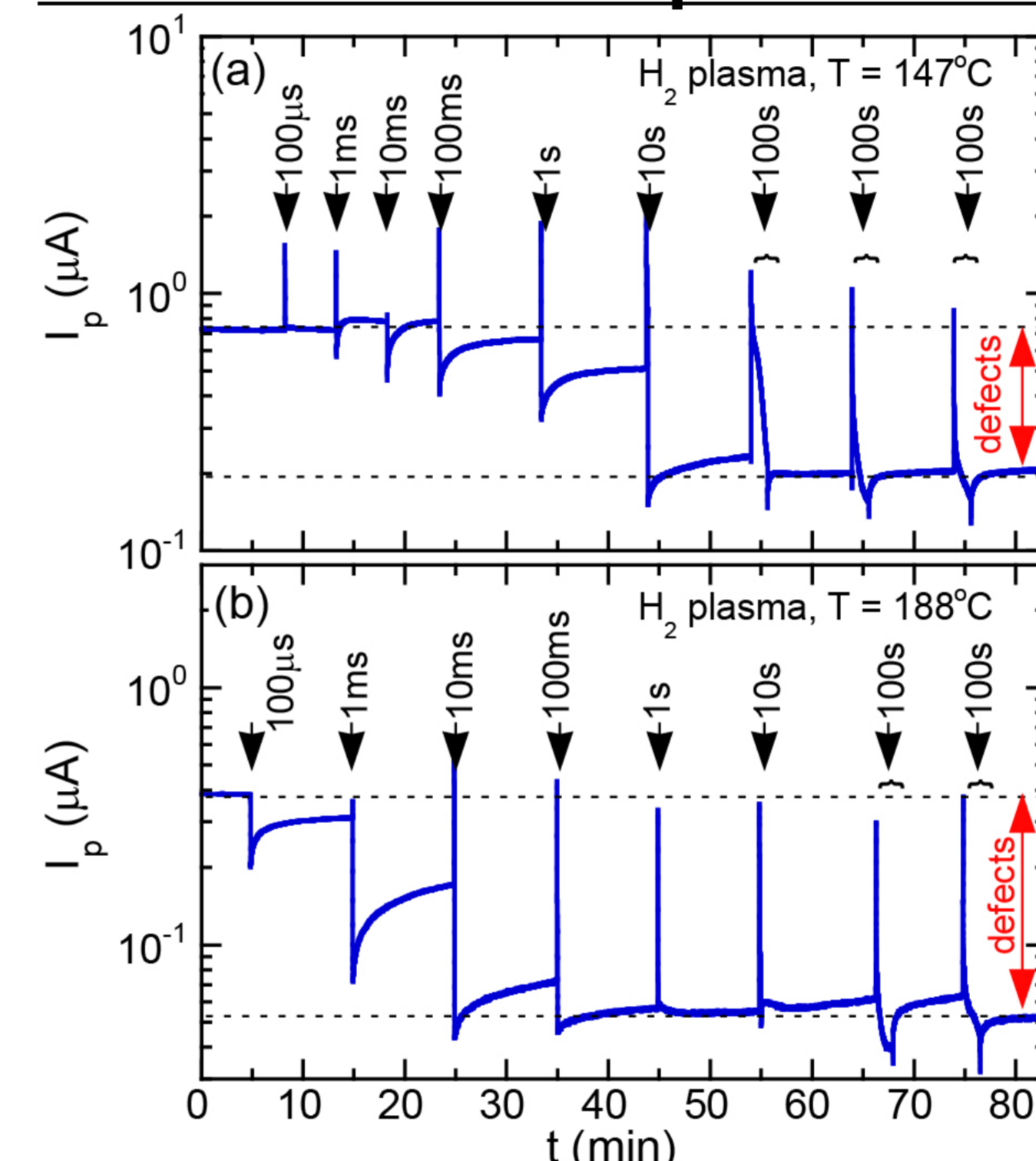
SHJ solar cell structure & minority carrier lifetime



- In SHJ solar cells, a-Si:H layer plays important roles in surface passivation & carrier selection.
- The lifetime, i.e., a measure for the surface passivation, varies throughout the fabrication process of SHJ solar cells

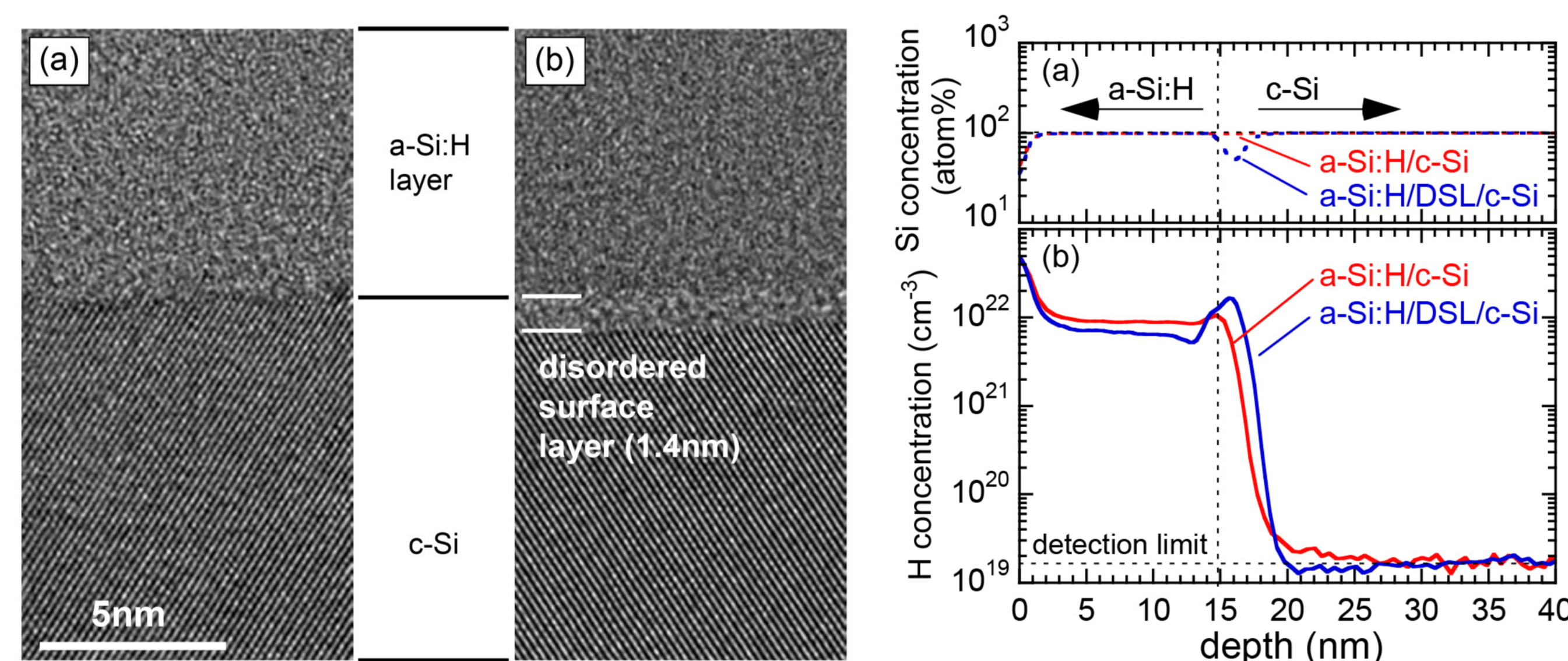
Experimental results

Time evolution of photocurrents



- The photocurrent (I_p) is reduced by a H_2 plasma treatment, indicating generation of defects (**defect generation**).
- The reduction of I_p is enhanced for a long- Δt treatment; more defects are generated.
- The generation of defects are pronounced for a short- Δt treatment under high-T conditions.
- During postannealing, I_p is increased, indicating the annihilation of defects. (**defect annihilation**)

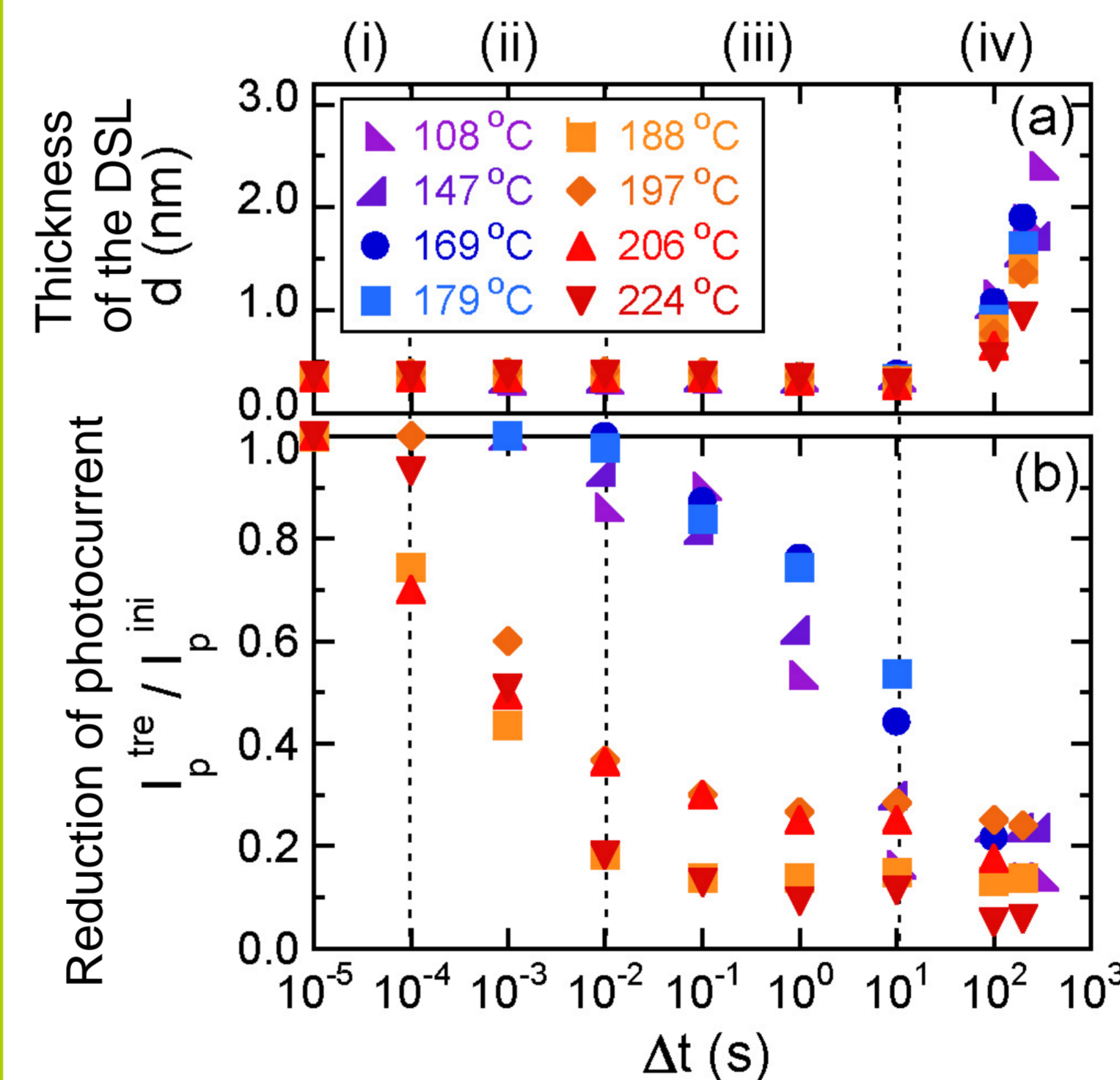
TEM and SIMS analysis



- TEM: (a) Normal sharp interface of a-Si:H/c-Si. (b) Formation of the disordered surface layer (DSL). The DSL is formed by a sufficiently long- Δt H_2 plasma treatment.
- SIMS: H atoms concentrate at the interface. The concentration is increased at the interface with DSL.

S. Nunomura et al., *Jpn. J. Appl. Phys.* 59, SHHE05 (2020).
S. Nunomura et al., *J. Appl. Phys.* 128, 033302 (2020).

Photocurrent reduction & DSL

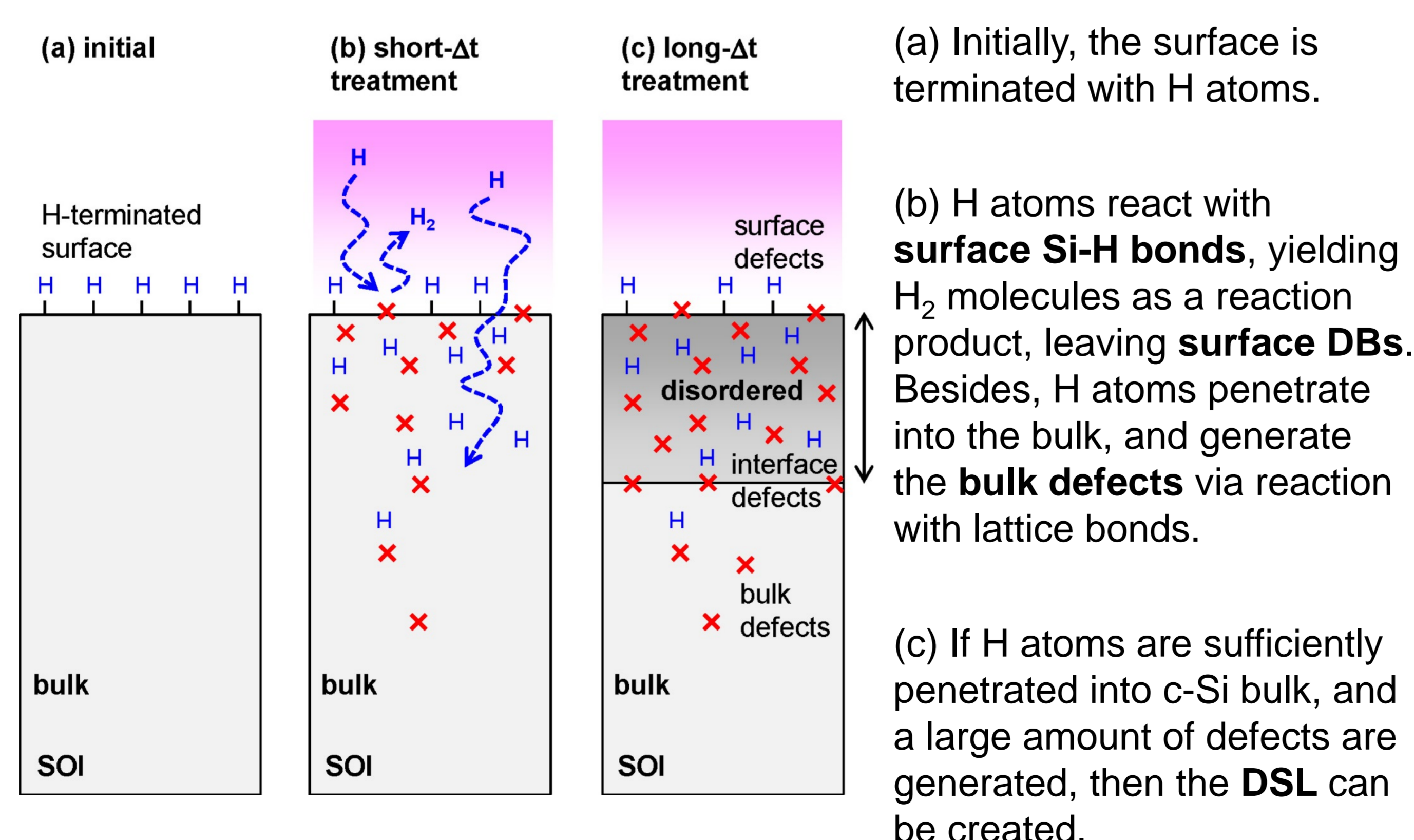


- (a) The **DSL** is formed only for long- Δt treatment. No DSL formation for short- Δt treatment.
- (b) The reduction tendency of I_p is classified into two groups: low-T and high-T groups.
- In the high-T group, I_p is decreased once Δt exceeds 10^{-4} s.
- In the low-T group, a longer- Δt treatment is required for generation of defects, possibly due to impurity adsorption.
- **Before formation of DSL, the H-induced electronic defects are created.**

S. Nunomura et al., *AIP advances*. 9, 045110 (2019).

S. Nunomura et al., *Appl. Phys. Express*. 12, 051006 (2019).

Model: Formation of H atom-induced defects & DSL



S. Nunomura et al., *AIP advances*. 9, 045110 (2019).

Summary

- **The generation and annihilation of H-induced defects** in crystalline silicon has been studied during H_2 plasma treatments, by using in-situ photocurrent measurement and spectroscopic ellipsometry.
- The H-induced defects are generated by a H_2 plasma treatment, and annihilated/recovered by postannealing.
- The generation of defects depends on treatment time and temperature.
- The electronic defects are created before the formation of DSL, i.e., nanometer-scale amorphized surface layer.
- The **surface and/or bulk defects** are partially recovered, but the **DSL** is not recovered.

Acknowledgements

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